

## 5 Integrated Circuit Technology

### 5.1 CMOS Manufacturing Process / CMOS Process Modules

### 5.2 Specific Aspects of sub 100 nm CMOS Technology

### 5.3 Future Transistor Concepts

**zfm**

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Chapter 5.3 - 1

## Possible Future Transistor Options

- Advanced Channel Materials
  - **III-V and Ge channel materials**
- Multi-Gate Fin Transistors
  - **Non planar architecture**
- Tunnel Transistors
  - **New transport mechanism**

**Each transistor structure has many significant challenges which will have to be successfully addressed if it is to become a serious contender to silicon MOSFET**

**zfm**

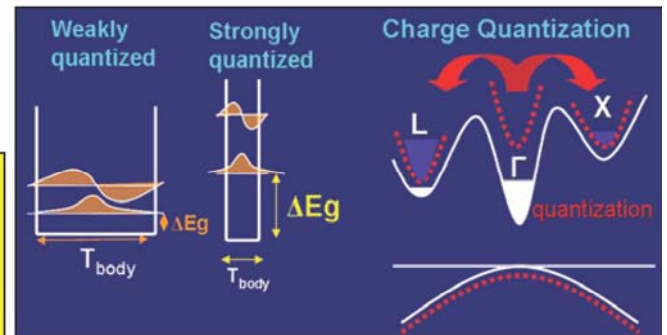
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Chapter 5.3 - 2

# III-V Materials for NMOS Channel?

- high  $\epsilon \rightarrow$  poor short channel effect (SCE)
- Low  $E_g \rightarrow$  large  $I_{off}$  (Junction)
- Low effective mass (+ high injection; - low  $Q_{INV}$ )

Material/Property	Si	Ge	GaAs	InAs	InSb
$m_{eff}^*$	0.19	0.08	0.067	0.023	0.014
$\mu_n$ (cm <sup>2</sup> /Vs)	1600	3900	9200	40,000	77,000
$E_G$ (eV)	1.12	0.66	1.42	0.36	0.17
$\epsilon_r$	11.8	16	12.4	14.8	17.7

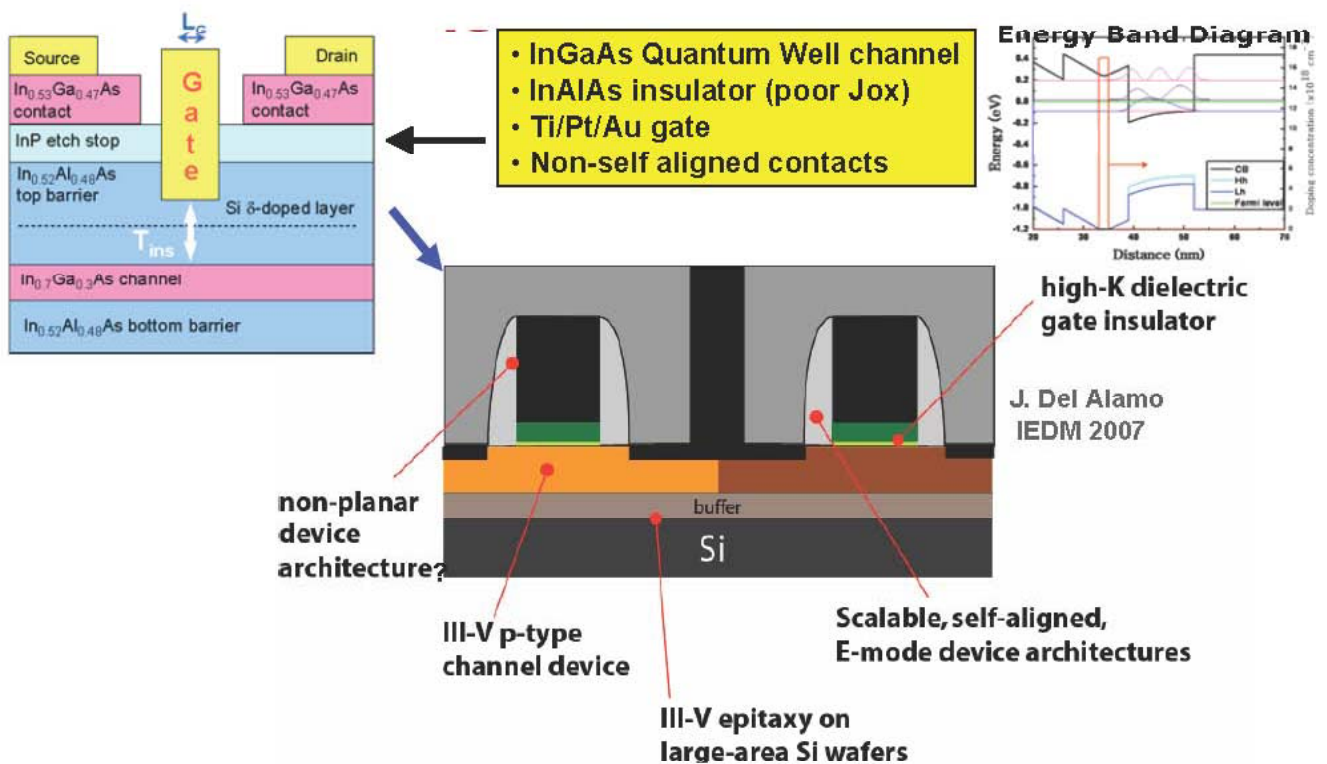


K. Saraswat et.al., IEDM 2006

Projecting III-V NMOS performance based on simplistic models could lead to erroneous performance assessment.

SCE: short channel effect

# The Grand Challenges for III-V CMOS



Source: Intel

# Ge Transistor- Back to the Future?

## • Advantages:

- + Best hole mobility (unlike III-V)
- + Si(Ge) already used in logic tech
- + Col-IV: Non-Polar

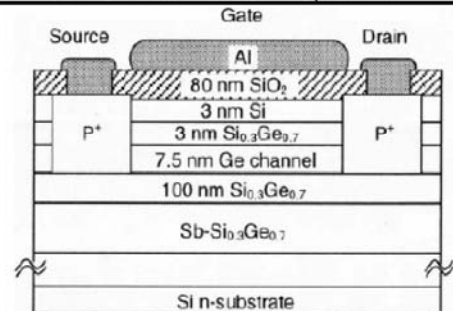
Material ⇒ Property ↓	Si	Ge	GaAs	InAs	InSb
Electron mobility	1600	3900	9200	40000	77000
Hole mobility	430	1900	400	500	850
Bandgap (eV)	1.12	0.66	1.424	0.36	0.17
Dielectric constant	11.8	16	12.4	14.8	17.7

K. Saraswat et.al., IEDM 2006.

## • Challenges:

- Reference device is highly strained silicon
- Poor HiK interface:
  - \* Need better understanding
  - \* Buried strained QW Ge
- Higher dielectric constant
  - \* Poorer SCE
- Worse parasitic resistance
  - \* Worse dopant activation

### Buried Strained Ge Quantum Well



(U. Tokyo, APL 2002)

## Possible Future Transistor Options

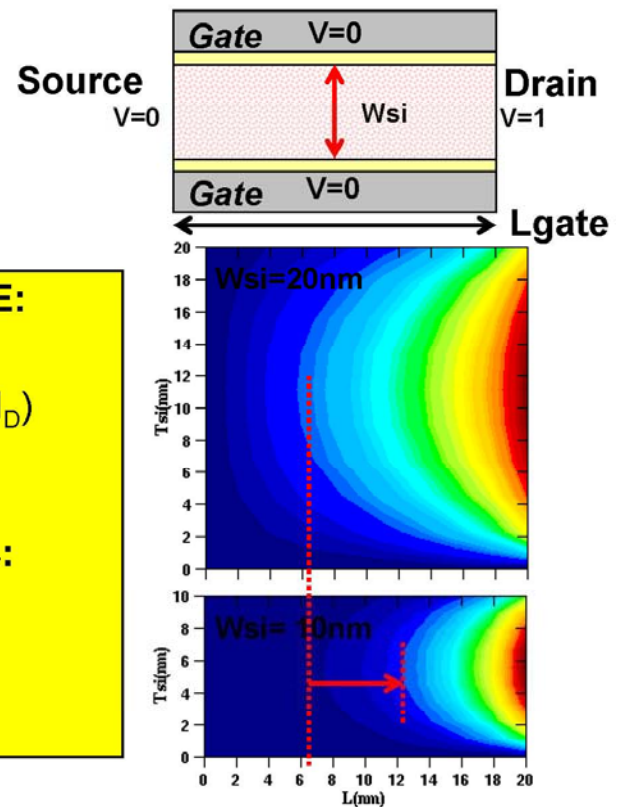
- Advanced Channel Materials
  - III-V and Ge channel materials
- ➔ • Multi-Gate Fin Transistors
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# Multi-Gate Transistor Architecture

$$\frac{\partial^2 \Phi}{\partial x^2} + \frac{\partial^2 \Phi}{\partial y^2} = \frac{qN_A}{\epsilon_{Si}}$$



## Multi-Gate Transistors have better SCE:

- Gates reduce spread of  $V_{\text{drain}}$   
Enables lower threshold voltage ( $\uparrow I_D$ )
- Enable lower channel doping ( $\uparrow \mu$ )

## Multi-Gate Transistors have lower $E_{\text{EFF}}$ :

- Optimum gate work function is away from band-edge leading to lower  $E_{\text{eff}}$  ( $\uparrow \mu$ )

SCE: short channel effect(s)

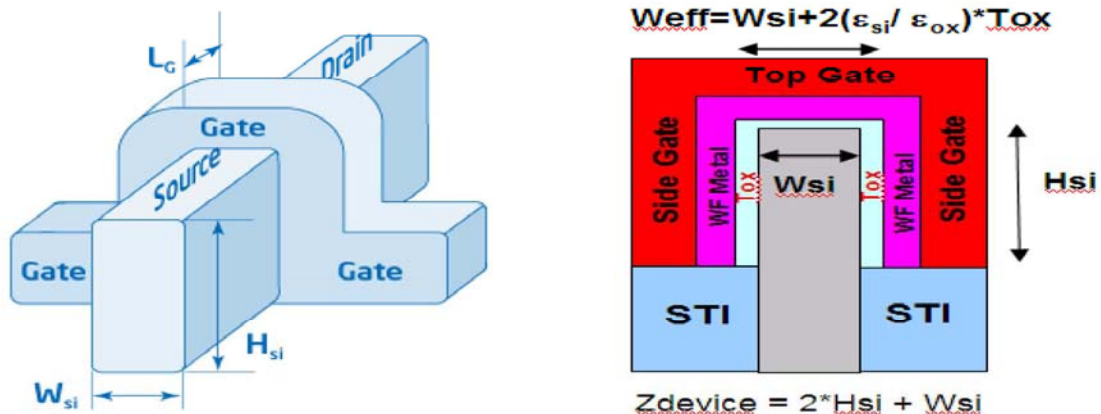
$E_{\text{eff}}$ : transverse (channel) electric field)

Source: Intel

# Multi-Gate Transistors Implementation

## Multi-Gate Fin Transistor:

- ++ Self Aligned structure for S/D
- Non-Planar structure

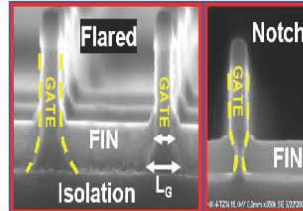
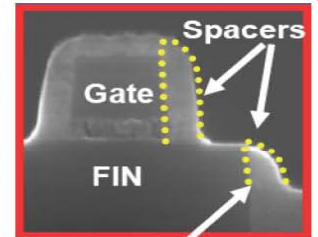
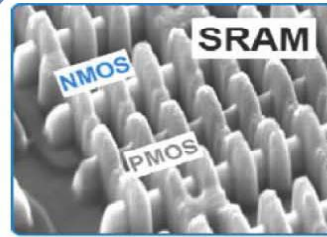


## Multi-Gate Fin Transistor

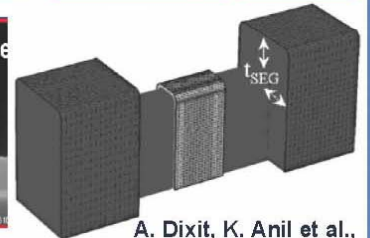
Source: Intel

# Top Challenges for Multi-Gate Fin Transistors

- **Implement High Strain in Fins?**  
Planar Ref= Highly strained  
4-5x p-mobility enhancement  
High level of fin strain NOT published to date
- **High Parasitics in Fin Transistors**  
Narrow fins lead to high Rext  
Fin architecture may also lead to higher fringe capacitance
- **Manufacturing worthy Patterning**  
Fin, Gate and Spacer patterning will be extremely challenging in a manufacturing environment
- **Design**  
Device Z increments quantized



J. Kavalieros et. al.  
VLSI Symp 2006



A. Dixit, K. Anil et al.,  
Solid State Electronics, 2006

- **Best published drive currents for Multi-Gate Fin Transistors are significantly lower than best published planar transistors to date**
- **Many significant challenges remain to be resolved for Fin Transistors**

Source: Intel

## Possible Future Transistor Options

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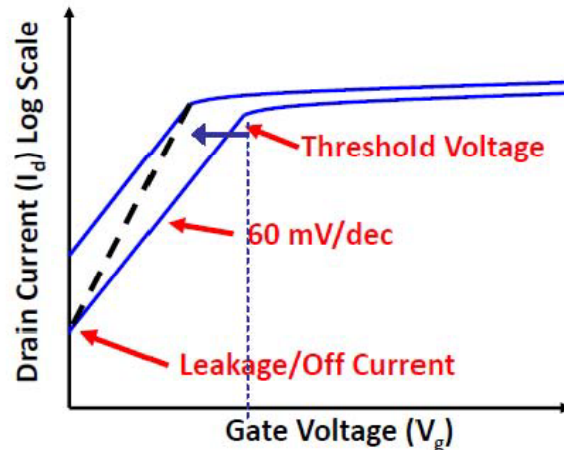
# Why we Need to Beat Sub-Threshold Slope of 60mV/decade?

$$I_D \sim (V_{CC} - V_{TH})$$

At very low  $V_{CC}$  we need small  $V_{TH}$  for reasonable drive

**BUT**

Sub-threshold slope is limited by thermal  $kT/q$  limit  
 $\rightarrow$   $I_{off}$  increases exponentially with  $V_{TH}$  scaling.



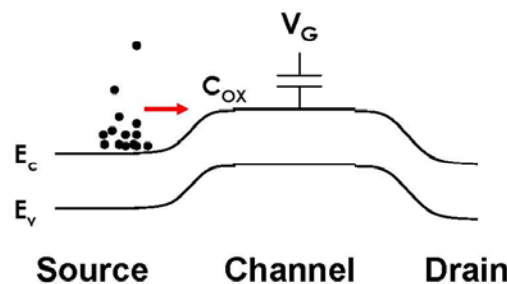
$$S = \left( \frac{d \log I_d}{dV_g} \right)^{-1} = 2.3 \frac{kT}{q} \left( 1 + \frac{C_d}{C_{ox}} \right) \geq 2.3 \frac{kT}{q}$$

**HOW TO BEAT  $kT/q$  limit?**

Leakage current increases **exponentially** as device is scaled

## Ultimate Frontier: Overcoming Thermal $kT/q$ Limit

C. Hu, STEEP Program



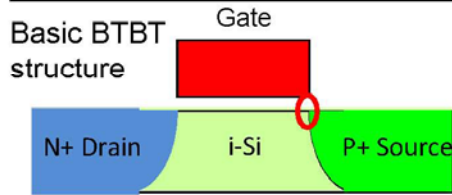
Electrons go over a potential barrier. Leakage current is determined by the Boltzmann distribution or 60 mV/decade, limiting MOSFET, bipolar, graphene MOSFET...

**How to overcome the limit:**

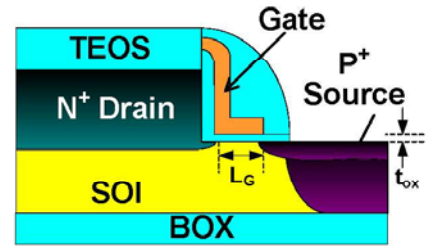
Let electrons go **through** the energy barrier,  
 not **over** it  $\rightarrow$  **Tunneling**



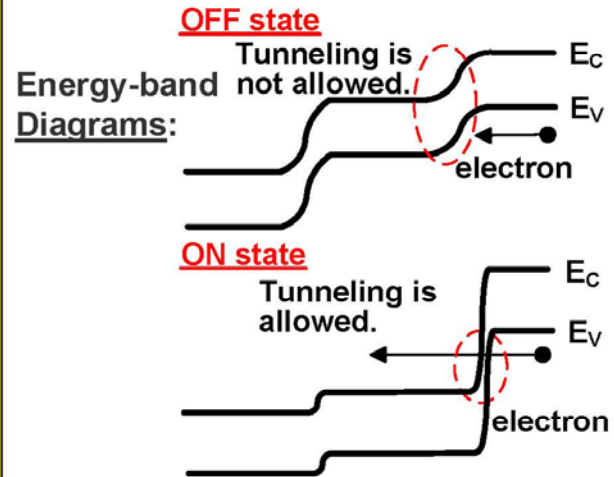
# Tunnel Transistor Concept and Challenges



## Structure:



- Device behaves like reverse bias pin diode
- Positive  $V_{gs}$  induces electron channel
- Band bending allows tunneling at source channel interface → Gate controlled band tunneling
- BTBT Transistor suffer from extremely poor drive current → **Need materials with more efficient tunneling**



W. Y. Choi et al. IEEE-EDL vol. 28, pp. 743-745, 2007

BTBT: band-to-band tunneling